

Advances in EUV Memory Manufacturing

Belinda Dube



Belinda Dube, Technology & Cost Analyst

Belinda Dube serves as a Technology & Cost Analyst at Yole SystemPlus, part of Yole Group.

Belinda's core expertise is memory technology, especially DRAM and 3D NAND flash memory. At the same time, she also investigates IC technologies as well as advanced packaging.

Belinda's mission is to develop reverse engineering & costing reports. She also works on custom projects, where she works closely with the laboratory team to set up significant physical & chemical analyses of innovative memory chips. Based on the results, Belinda identifies and analyzes the overall manufacturing process and all technical choices made by the memory makers.

In addition, a significant portion of her mission is dedicated to a strategic technology watch, where her aim is to identify innovative memory chips and manufacturing processes. Based on her expertise, Belinda updates internal simulation tools and runs custom training sessions and demos with industrials.

She regularly has an opportunity to reveal pertinent results during key onsite presentations and webcasts.

Prior to System Plus Consulting, Belinda had the opportunity to work on several R&D projects dedicated to MEMS technologies and new substrates at INSA (Lyon, France).

Belinda holds a master's degree in Instrumentation & Nanotechnology Engineering from INSA (France).

Email: belinda.dube@yolegroup.com

TABLE OF CONTENT

- ❖ MARKET ANALYSIS
- ❖ DRAM TECHNOLOGY ANALYSIS
- ❖ COST SYNTHESIS
- ❖ EUV BENEFITS
- ❖ CONCLUSION

MARKET ANALYSIS DRAM MARKET & EVOLUTION

DRAM MEMORY MARKET

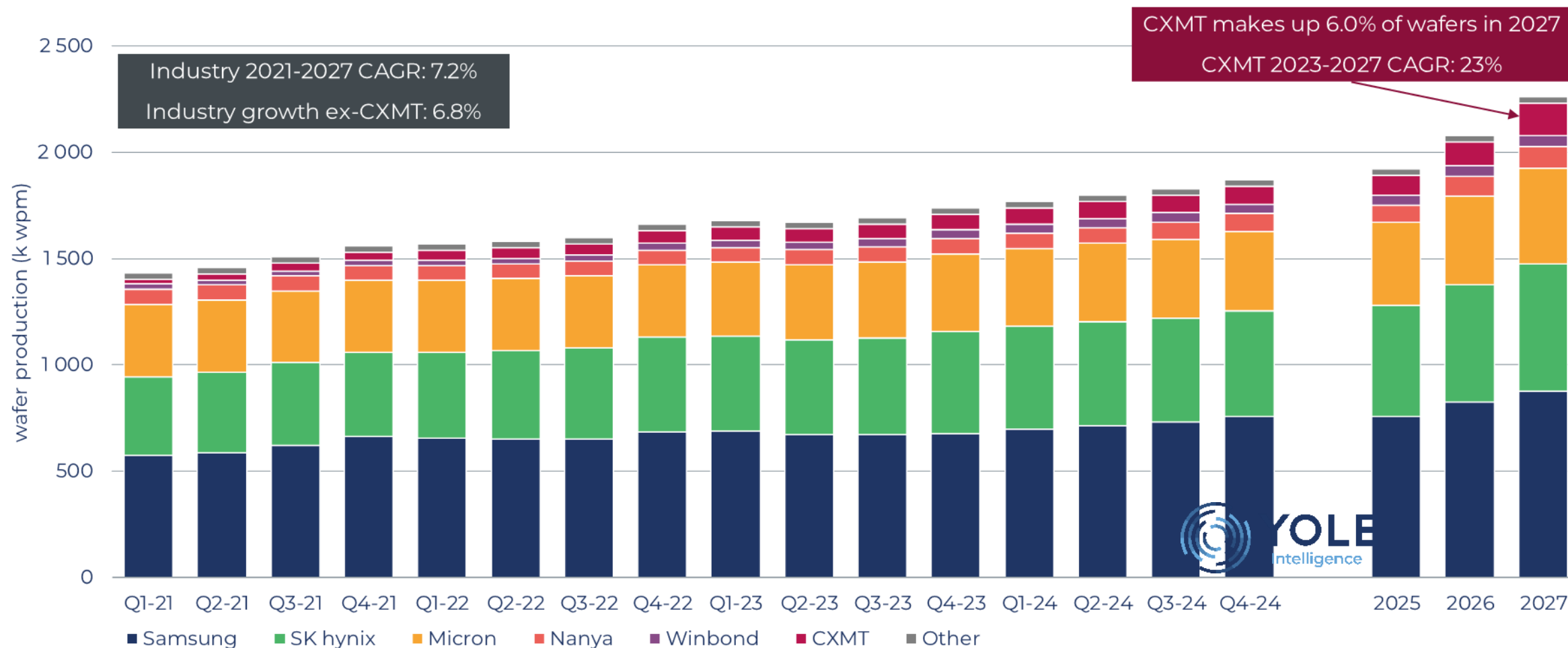


YOLE
SystemPlus



Flash Memory Summit

- Over the long-run wafer production will increase to keep pace with bit demand.



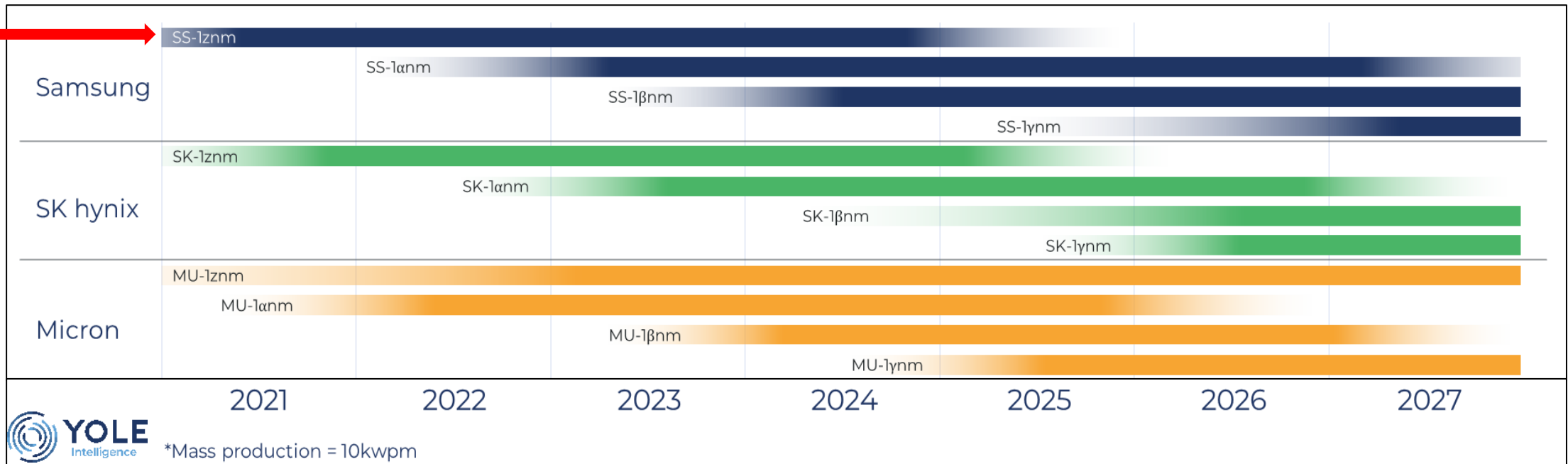
DRAM Market Monitor Q2 2022

©2022 by YOLE Intelligence

DRAM EVOLUTION

- EUV Lithography has been adopted to overcome the limitations of DRAM scaling in memory manufacturing.
- Samsung is the first in the industry to successfully apply EUV processing and has been mass-producing specific EUV-applied products.

EUV



DRAM Market Monitor Q2 2022

©2022 by YOLE Intelligence



YOLE
SystemPlus



Flash Memory Summit

DRAM TECHNOLOGY ANALYSIS

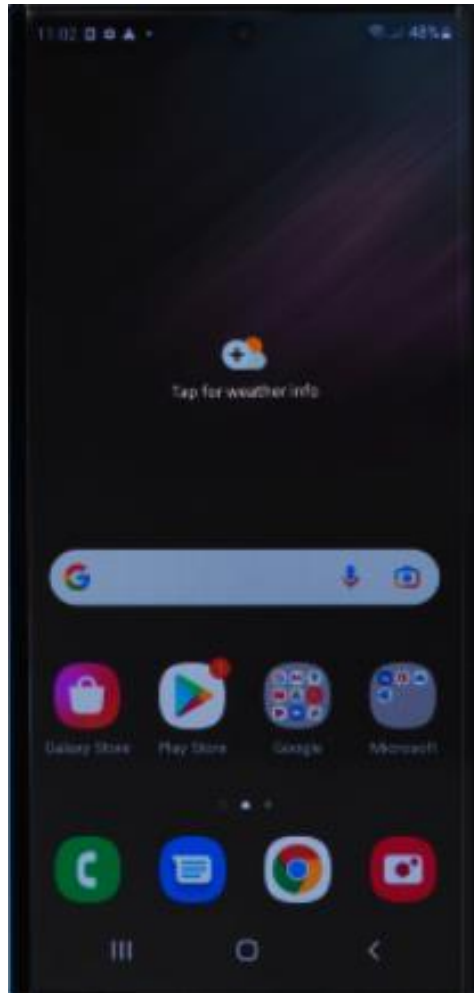
SAMSUNG DRAM



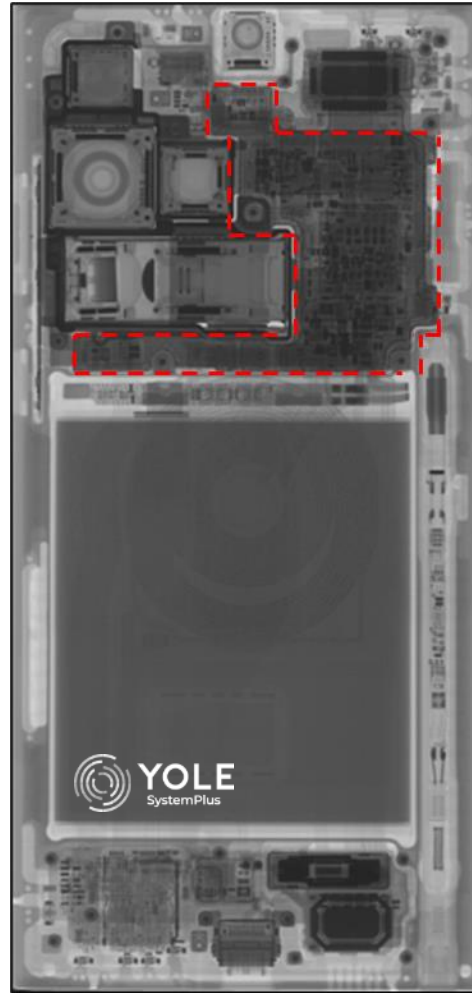
YOLE
SystemPlus



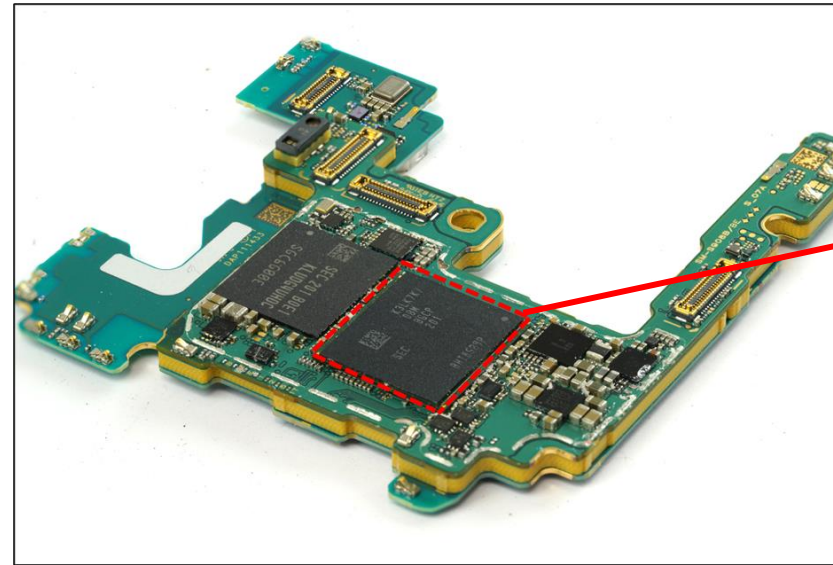
Flash Memory Summit



*Samsung Galaxy S22 Ultra 5G
(International Version)*
©2022 by YOLE SystemPlus



*Samsung Galaxy S22 Ultra 5G –X-Ray
Image (International Version)*
©2022 by YOLE SystemPlus



Main PCB on Samsung Galaxy S22 Ultra 5G
©2022 by YOLE SystemPlus



Samsung LPDDR5 Frontside View
©2022 by YOLE SystemPlus

- **Huawei Honor Magic3 Pro 5G**
- **SAMSUNG Galaxy S22+ 5G**
- **SAMSUNG Galaxy S22 Ultra 5G**
- **XIAOMI 12 Pro**
- **OnePlus 9 Pro 5G**
- **Huawei P50 Pro**
- **ASUS Zenfone 8 Flip**
- **XIAOMI Black Shark 4**
- **SAMSUNG Galaxy S21 5G**
- **GOOGLE Pixel 6**
- **SAMSUNG Galaxy Z Flip3**
- **XIAOMI POCO F4 GT**

SAMSUNG DRAM



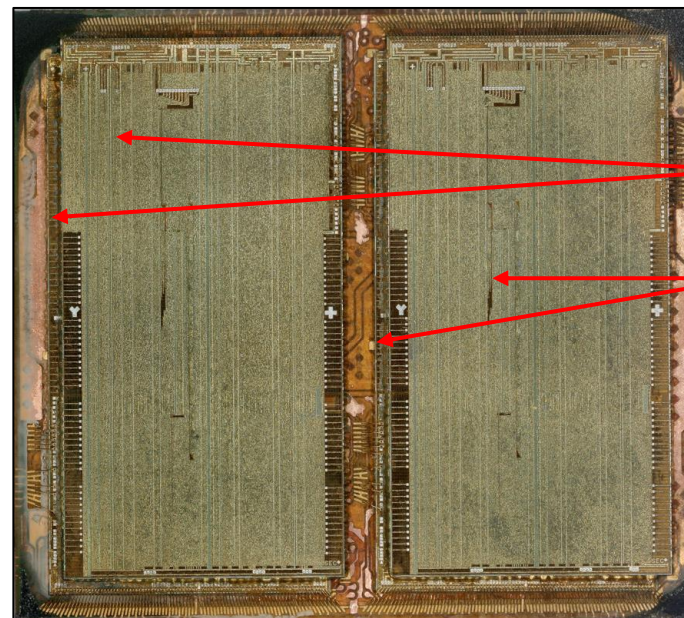
YOLE
SystemPlus



Flash Memory Summit



Samsung Memory 8GB Package
©2022 by YOLE SystemPlus



Samsung Memory 8GB –Package Opening
©2022 by YOLE SystemPlus

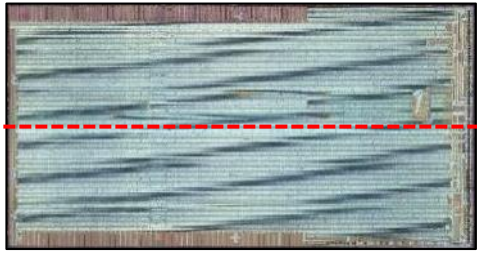


Samsung Memory Package Cross Section – Optical View
©2022 by YOLE SystemPlus

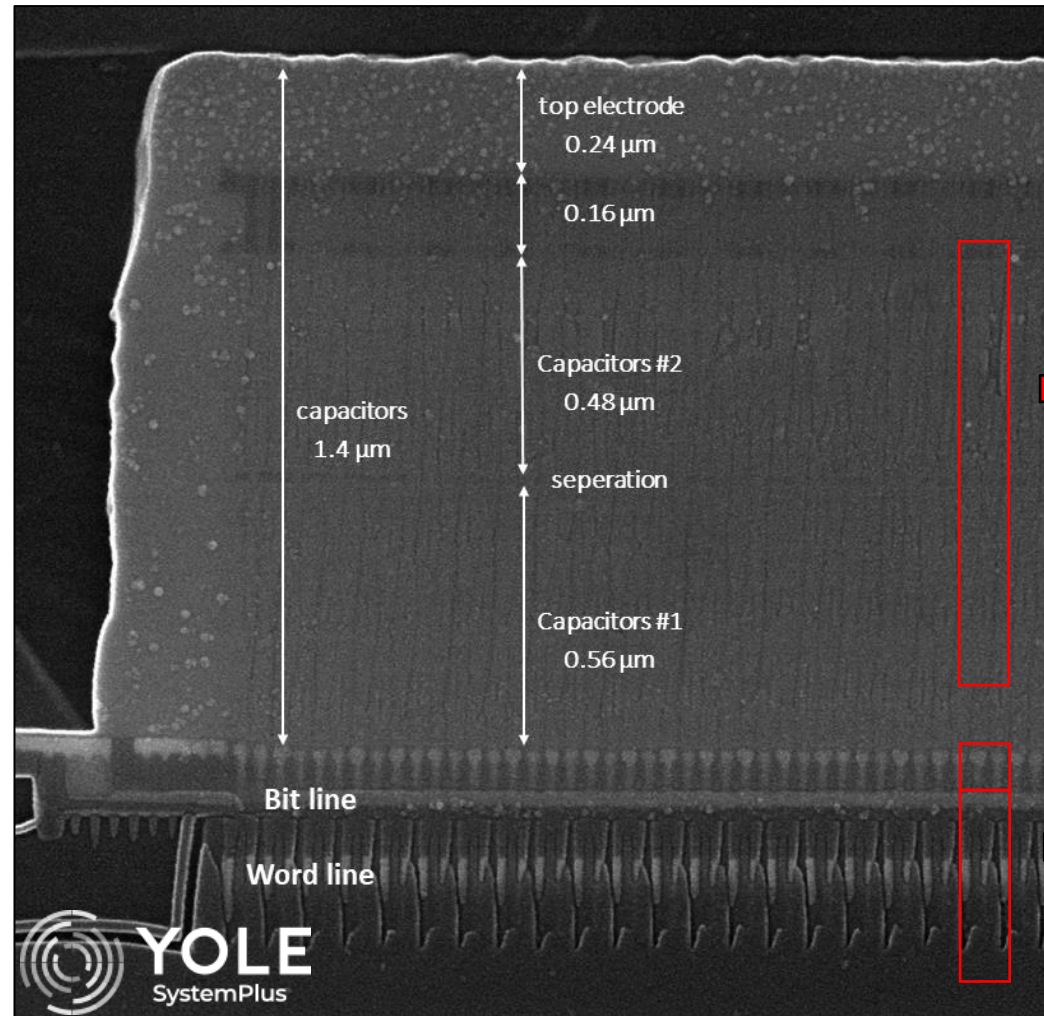
- Dies in package : 4
- Die capacity: 16Gb



SAMSUNG DRAM EUV LITHOGRAPHY

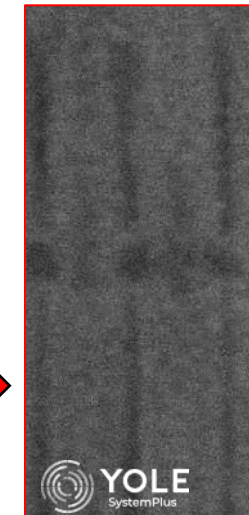


Die Cross Sectioning
©2022 by YOLE SystemPlus



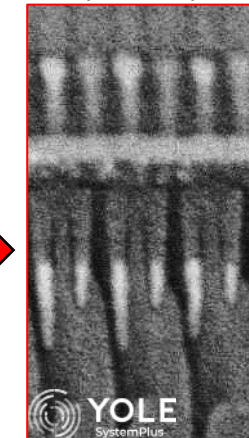
Die Cross Section – SEM View
©2022 by YOLE SystemPlus

Capacitor opening



Capacitors – SEM View
©2022 by YOLE SystemPlus

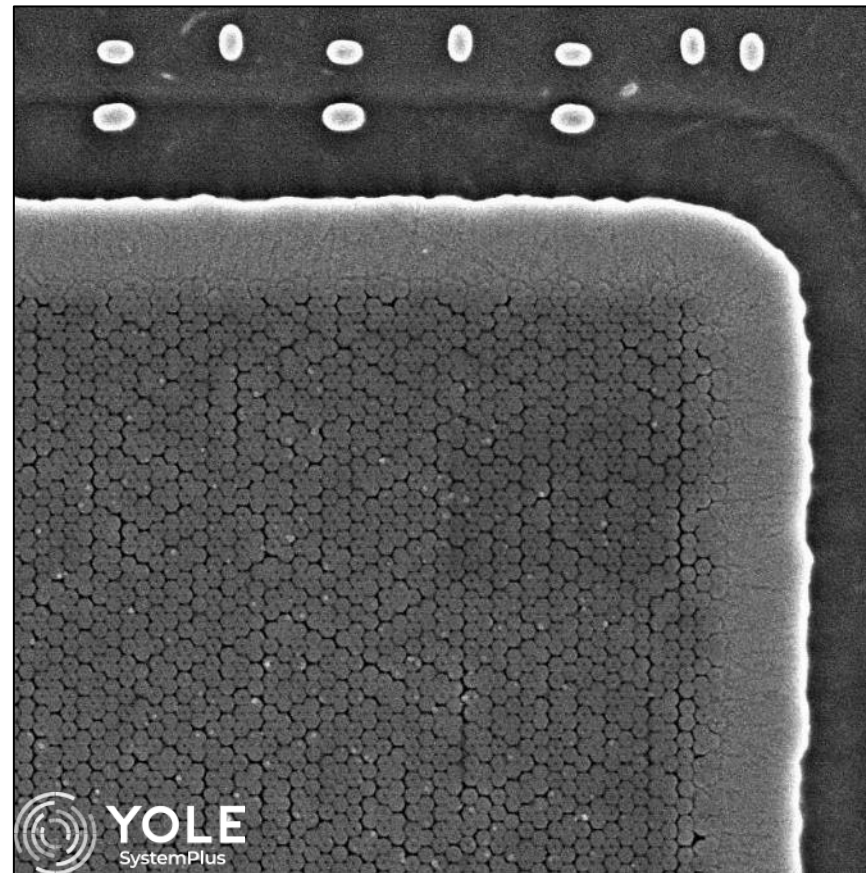
Wordline & contacts



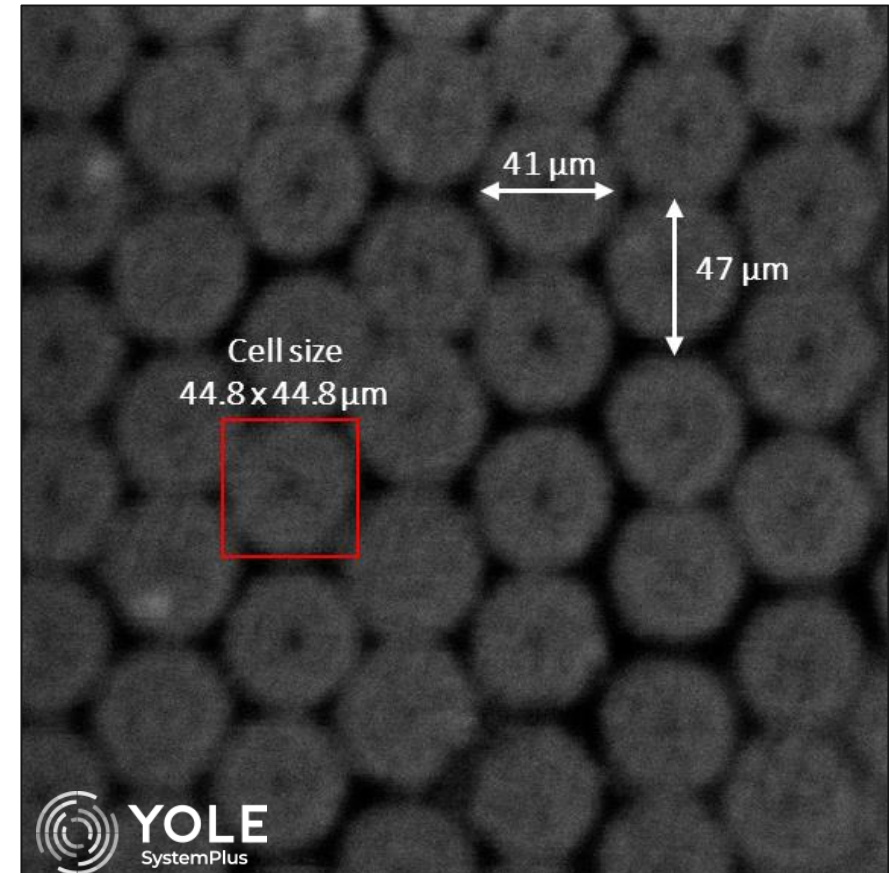
Contacts & Wordlines – SEM View
©2022 by YOLE SystemPlus

SAMSUNG DRAM EUV LITHOGRAPHY

- Cell size $\sim 0.018 \mu\text{m}^2$
- Reduced Cell size results in higher density.



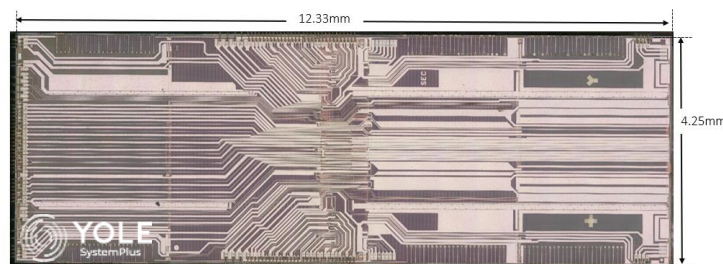
Die Delaying SEM View
©2022 by YOLE SystemPlus



Die Delaying SEM View
©2022 by YOLE SystemPlus



SAMSUNG EUV DRAM vs NON EUV DRAM



Samsung LPDDR5 (1y gen)

©2022 by YOLE SystemPlus



Samsung LPDDR5 (1z gen)

©2022 by YOLE SystemPlus

	Samsung LPDDR5 (non EUV)	Samsung LPDDR5 (EUV)	
Die capacity	12Gb	16Gb	↑ 30%
Die dimensions	12.3 x 4.2 mm	10.8 x 5.6 mm	
Die area	52 mm ²	60 mm ²	
Die density	0.23 Gb/mm ²	0.264 Gb/mm ²	↑ 15%
Potential dies/wafer	1,204	1,048	
Potential capacity /wafer	14,448 Gb/300mm wafer	16,768 Gb/300mm wafer	↑ 15%



DRAM COST ANALYSIS

SAMSUNG COST ANALYSIS



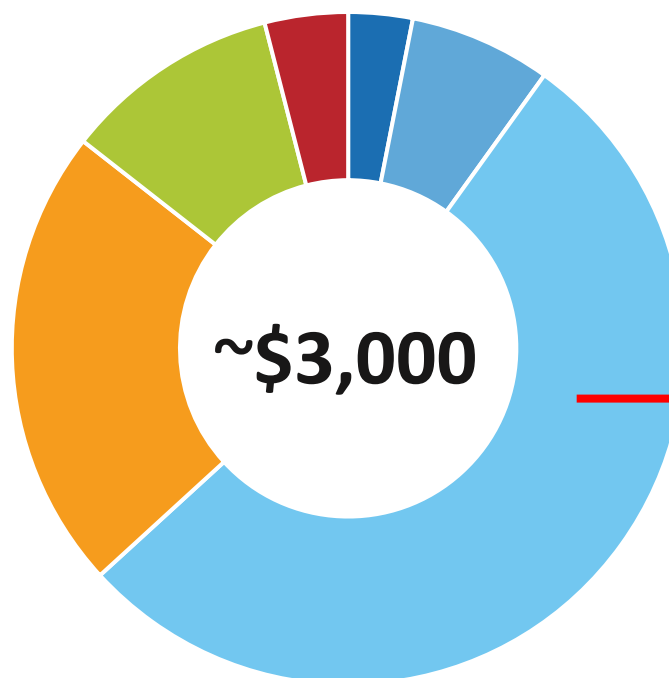
YOLE
SystemPlus



Flash Memory Summit

DRAM MEMORY FRONT END WAFER COST BREAKDOWN

- Si Wafer
- Clean Room Cost
- Equipment Cost
- Consumable Cost
- Labor Cost
- Yield losses Cost



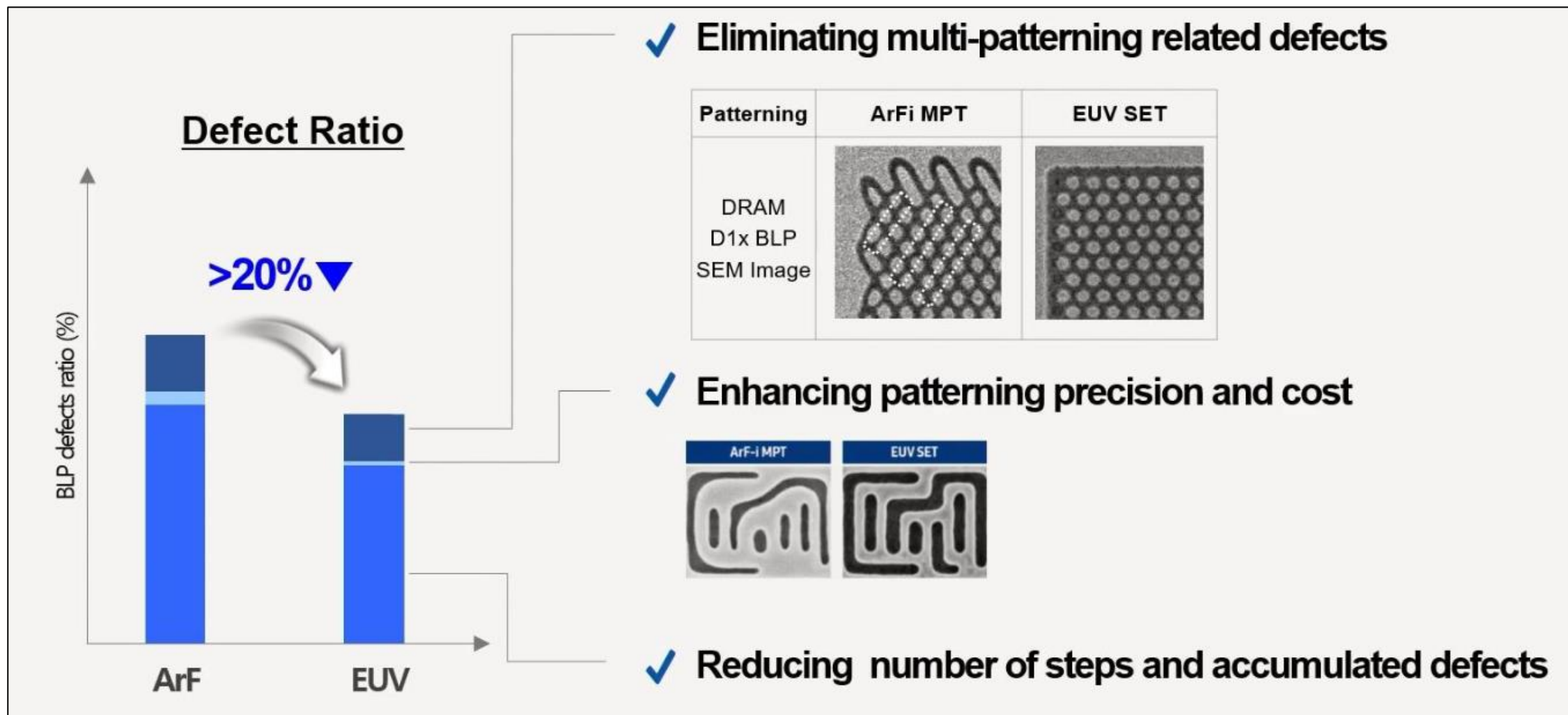
SAMSUNG EUV BENEFITS



YOLE
SystemPlus



Flash Memory Summit



Source : Samsung Investor Meeting 2020

SAMSUNG EUV BENEFITS

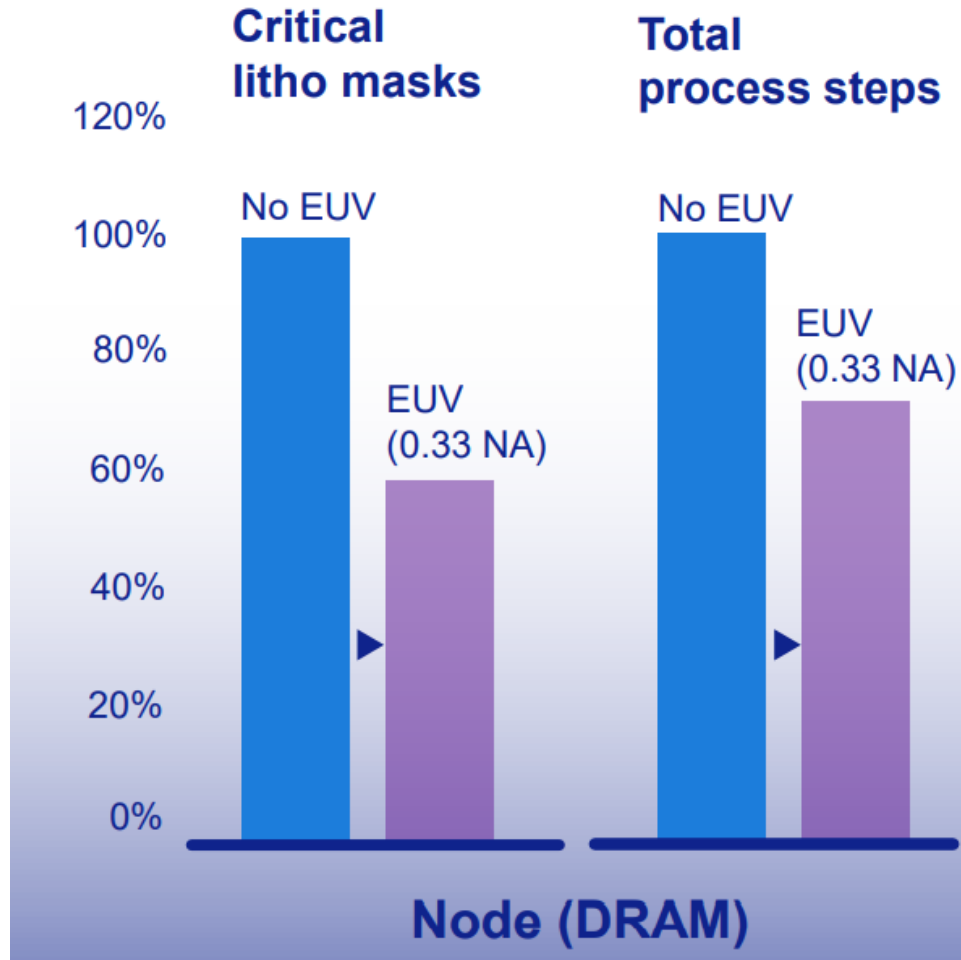


YOLE
SystemPlus



Flash Memory Summit

ASML



Source : ASML

EUV lowers the lithography and total number of process steps, resulting in :

- Reduced Defect
- Shorter Cycle time
- Cost reduction
- Higher productivity per wafer
- Density increase



BENEFITS

- IMPROVED YIELDS
- HIGHER DENSITY DIES
- REDUCED PRODUCTION TIME
- COST REDUCTION

DISADVANTAGES

- HUGE INVESTMENTS IN EQUIPEMENT
- EUV WAVELENGTH CAN BE EASILY ABSORBED
- EUV EQUIPEMENT FOOTPRINT



YOLE
SystemPlus



Flash Memory Summit

CONCLUSION

CONCLUSION



YOLE
SystemPlus



Flash Memory Summit

- EUV lithography process allows the memory to store more capacity within the same area to meet increasing demands for high capacity.
- EUV can greatly enhance the feature density of chips without heavy reliance on multi-patterning, Multi patterning to single patterning reduces the processing steps and time.
- Samsung has been the first to introduce EUV lithography patterning in DRAM memory, in the future other players will join and adopt EUV process.
- Heavy investments is necessary for this process adoption.